



INFORMATION DISCLOSURE STATEMENT BY APPLICANT PTO-1449	DOCKET NO. 10020/29701	SERIAL NO. 10/690,704
	APPLICANT SHTEIN et al.	
	FILING DATE October 23, 2003	GROUP 1762

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
JA	4,788,082	November 29, 1988	Schmitt			
JA	5,256,205	October 26, 1993	Schmitt, III et al.			
JA	5,650,197	July 22, 1997	Halpern			

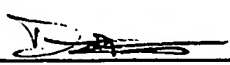
FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
JA	A.K. Rebrov, "Free Jets in Vacuum technologies", J. Vac. Sci. Technol., A 19(4), pp. 1679-1687, Jul/Aug 2001.
JA	J. Fernandez de la Mora, "Surface impact of seeded jets at relatively large background densities", J. Chem. Phys, 82 (7), pp. 3453-3464, April 1, 1985.
JA	J. Fernandez de la Mora et al., "Aerodynamic focusing of heavy molecules in seeded supersonic jets", J. Chem. Phys, 91 (4), pp. 2603-2615, August 15, 1989.
JA	A.V. Vasenkov et al., "Flow-field properties under deposition of films from low-density jets", J. Appl. Phys., 77(9), pp. 4757-4764, May 1, 1995.
JA	A.V. Vasenkov, et al., "Monte Carlo simulation of an amorphous hydrogenated silicon film deposition from a gas jet activated by an electron beam", Journal of Applied Physics, Volume 83, Number 7, pp. 3926-3928, April 1, 1998.
JA	Karl-Heinz Muller, "Role of Incident Kinetic Energy of Adatoms in Thin Film Growth", Surface Science Volume 184 (1987) pp. L375-L382.
JA	M. Lebedev et al., "Simple self-selective method of velocity measurement for particles in impact-based deposition", J. Vac. Sci. Technol., A 18(2), pp. 563-566, Mar/Apr 2000.
JA	B.L. Halpern et al., "Multiple Jets and moving substrates: Jet Vapor Deposition of multicomponent thin films", J. Vac. Sci. Technol., A 12 (4), pp. 1623-1627, July/August 1994.
JA	D. Lubben, et al., "Growth and doping of Si layers by molecular-jet chemical vapor deposition: Device fabrication", Appl. Phys. Lett., 71(19), pp. 2812-2814, November 10, 1997.

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
ES		B.L. Halpern et al., "Gas jet deposition of thin films", Applied Surface Science 48/49, pp. 19-26, 1991.
ES		D. Eres, "High-speed epitaxy using supersonic molecular jets", Mat. Res. Soc. Symp. Proc., Vol. 201, 1991.
ES		G. Eres, "Application of Supersonic Molecular Jets in Semiconductor Thin Film Growth", Critical reviews in solid state and materials sciences, Volume 23, Issue 4, pp. 275-322, 1998.
ES		Zhang et al., "Jet Vapor Deposition of Organic Guest-Inorganic Host Thin Films for Optical and Electronic Applications", Journal of Electronic Materials, Volume 23, No. 11, pp. 1239-1244, Nov. 1994.

EXAMINER		DATE CONSIDERED	1/31/05
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			



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PTO-1449**

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APPLICANT
FORREST et al.

FILING DATE
October 23, 2003

GROUP
Not Yet Assigned

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>JA</i>	6,596,443	July 22, 2003	Weaver et al.			
<i>JA</i>	6,214,631	April 10, 2001	Burrows et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.

EXAMINER <i>DA</i>	DATE CONSIDERED <i>2/1/05</i>
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